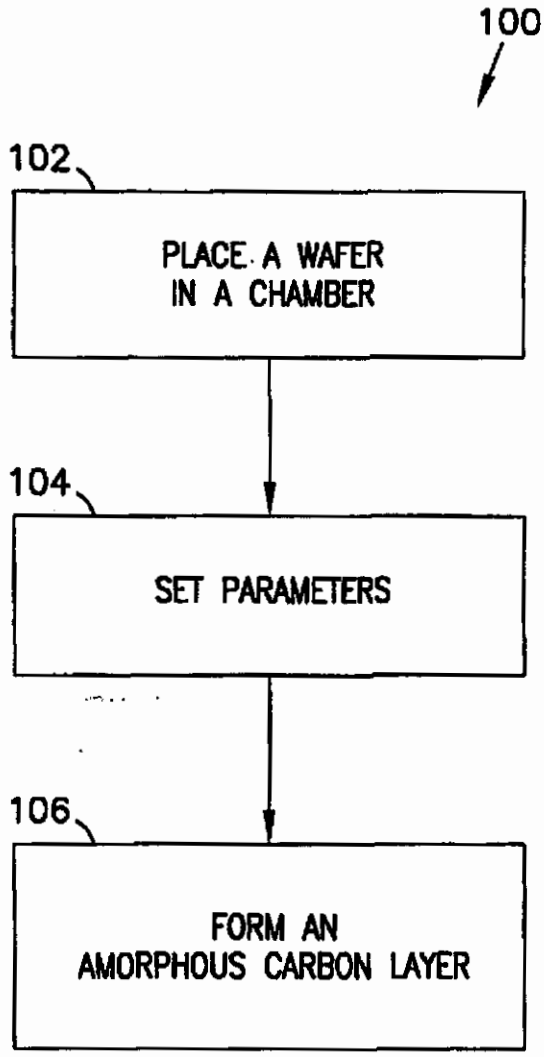

100
102
PLACE A WAFER IN A CHAMBER
104
SET PARAMETERS
106
FORM AN AMORPHOUS CARBON LAYER

FIG. 1A

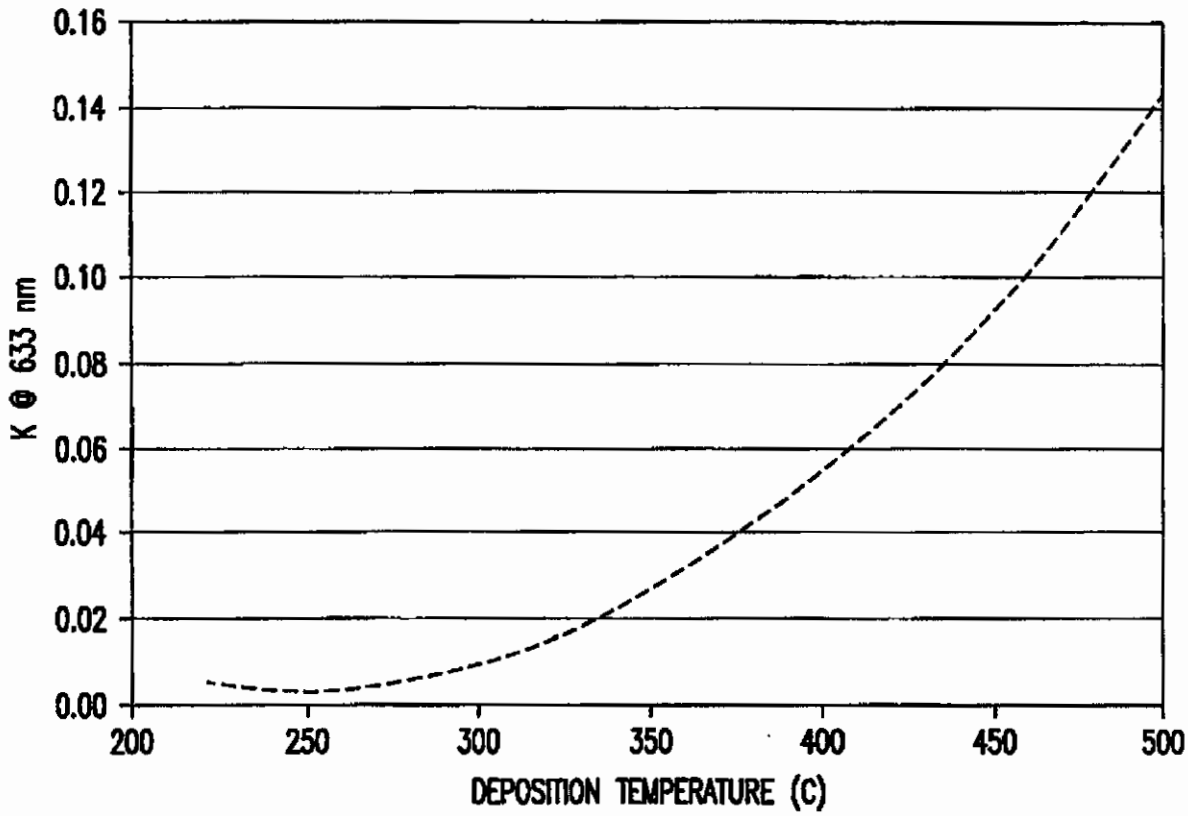

0.16
0.14
0.12
0.10
0.08
0.06
0.04
0.02
0.00
K @ 633 nm
200
250
300
350
400
450
500
DEPOSITION TEMPERATURE (C)

FIG. 1B

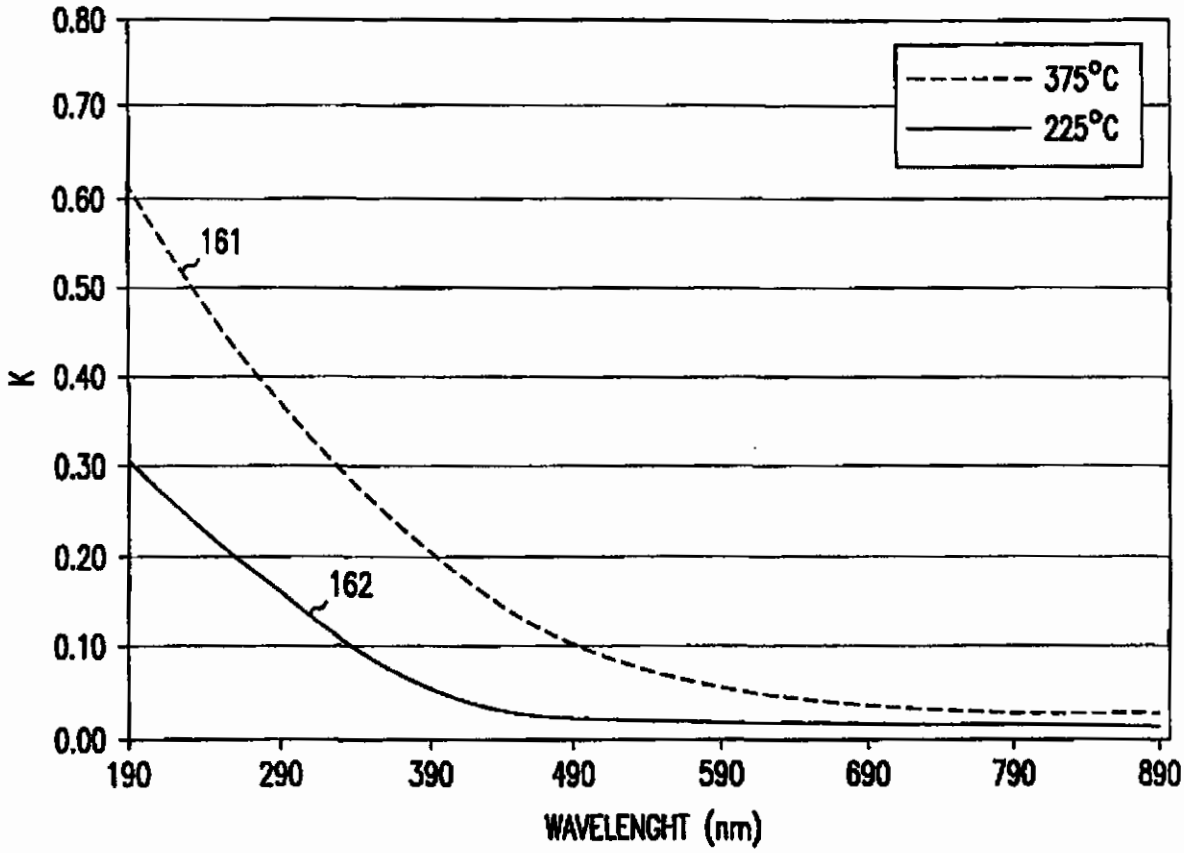

0.80
0.70
0.60
0.50
0.40
0.30
0.20
0.10
0.00
K
375°C
225°C
161
162
190
290
390
490
590
690
790
890
WAVELENGHT (nm)

FIG. 1C

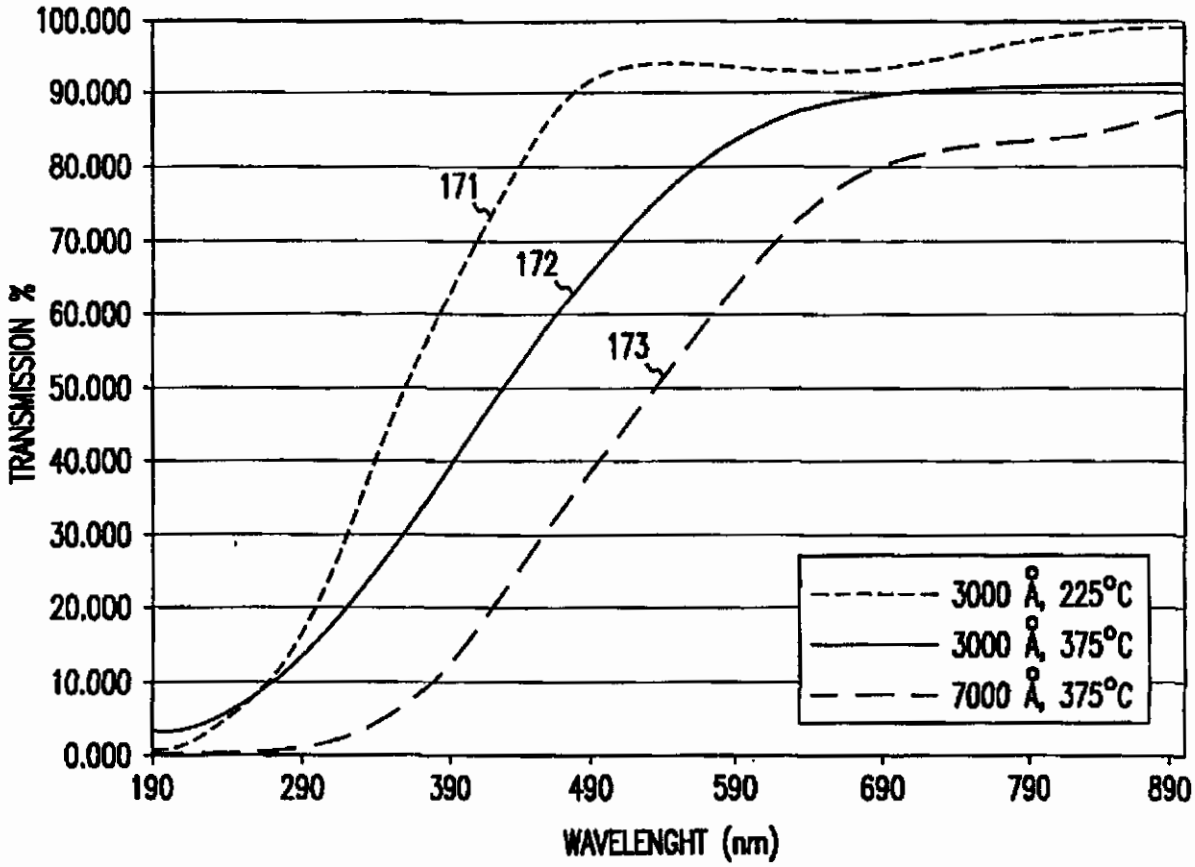

100.000
90.000
80.000
70.000
60.000
50.000
40.000
30.000
20.000
10.000
0.000
TRANSMISSION %
171
172
173
3000 Å, 225°C
3000 Å, 375°C
7000 Å, 375°C
190
290
390
490
590
690
790
890
WAVELENGHT (nm)

FIG. 1D

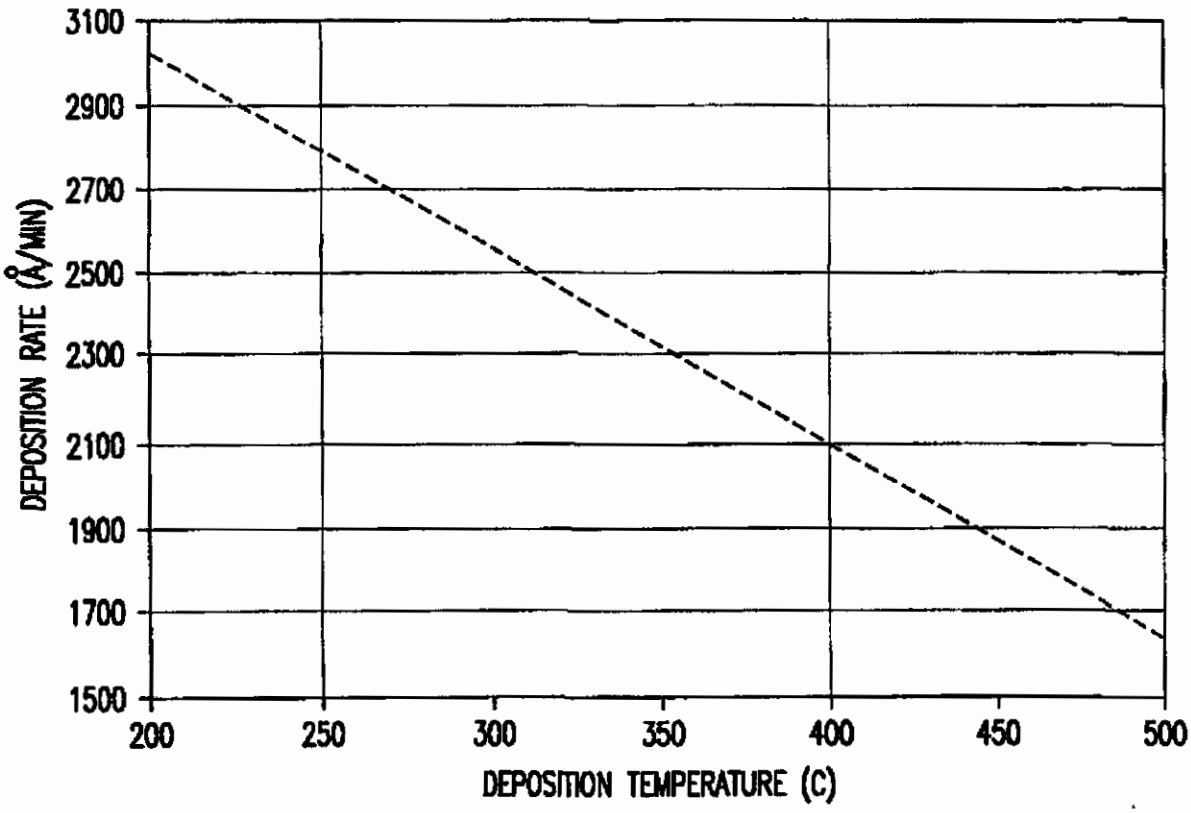

3100
2900
2700
2500
2300
2100
1900
1700
1500
DEPOSITION RATE (Å/MIN)
200
250
300
350
400
450
500
DEPOSITION TEMPERATURE (C)

FIG. 1E

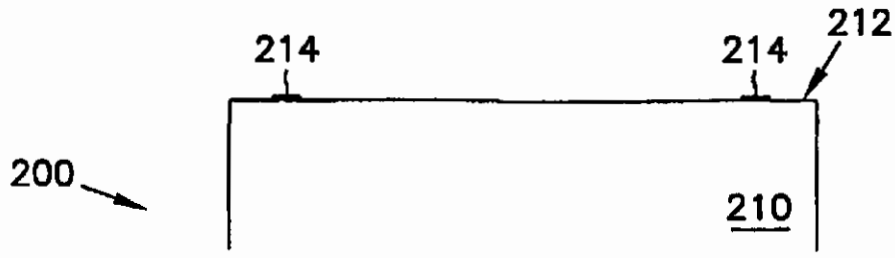



FIG. 2

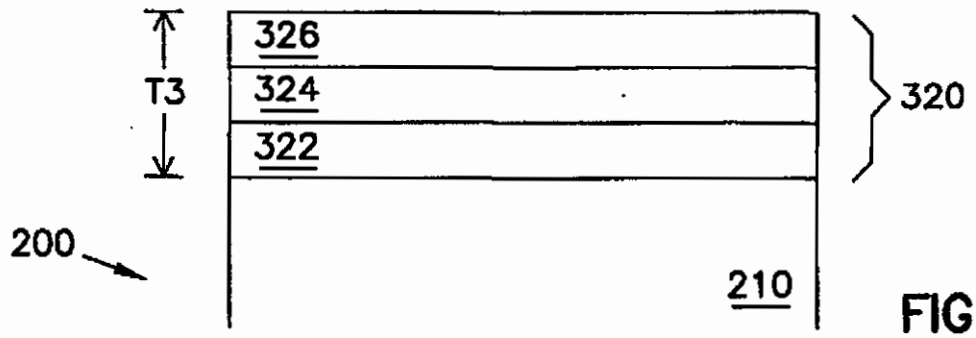



FIG. 3

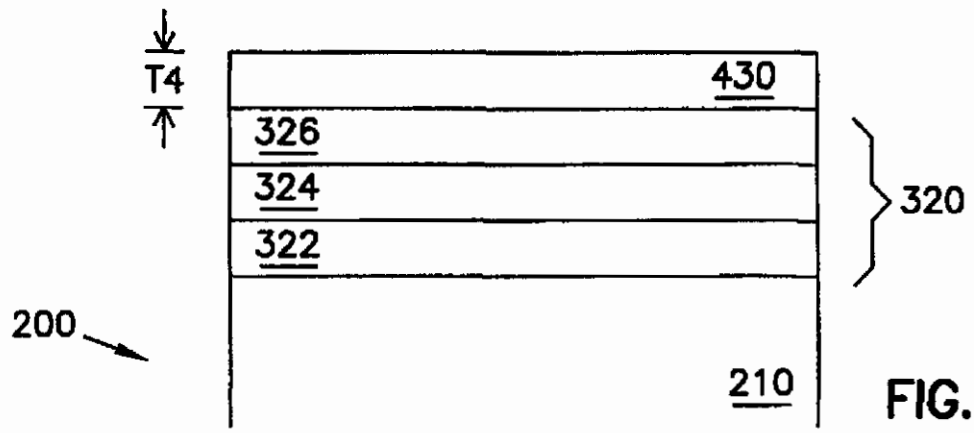



FIG. 4A

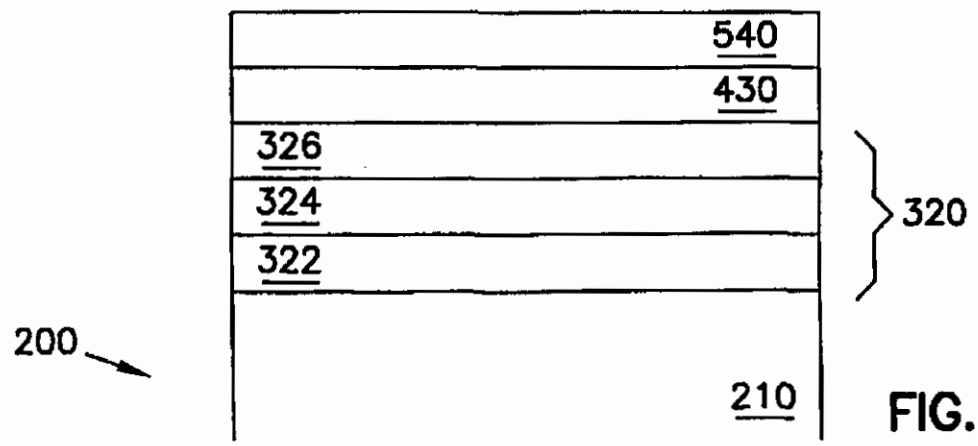



FIG. 4B

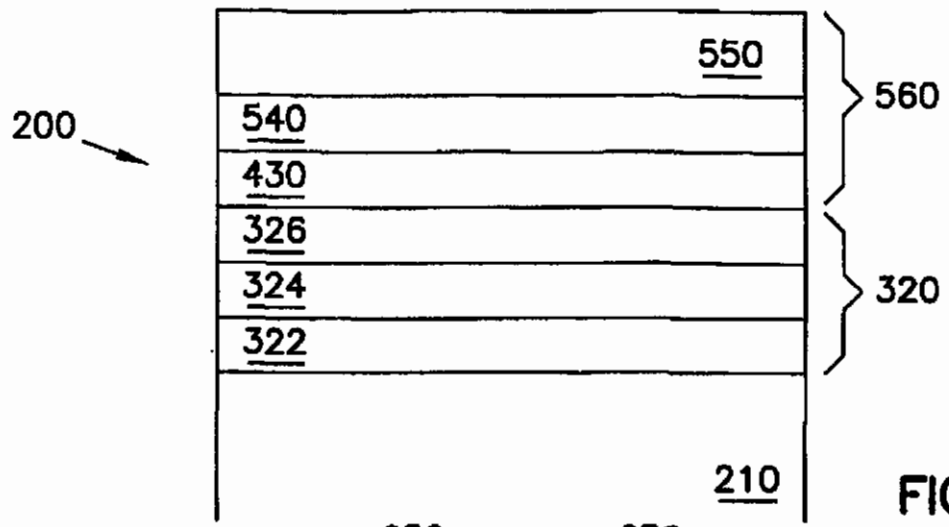



FIG. 5

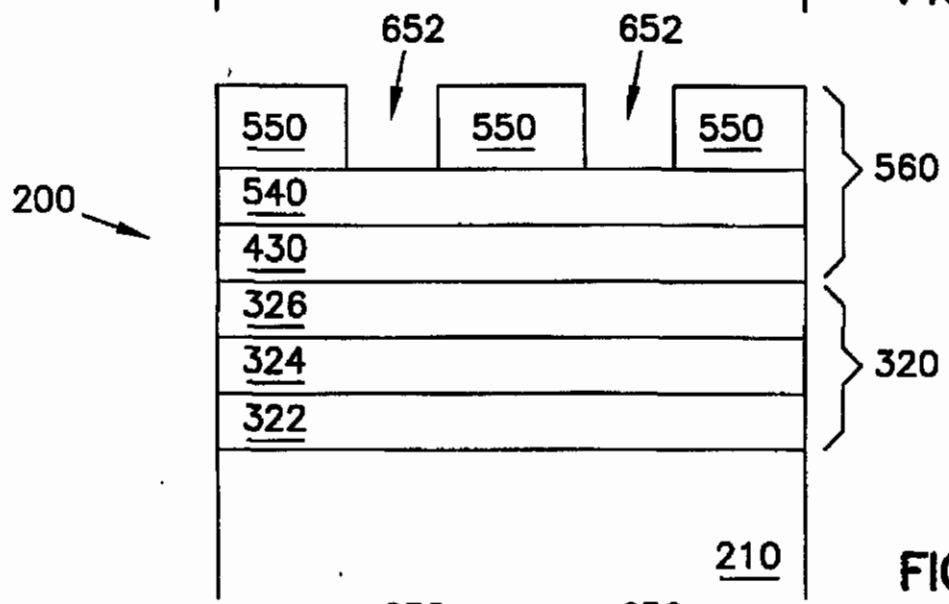



FIG. 6

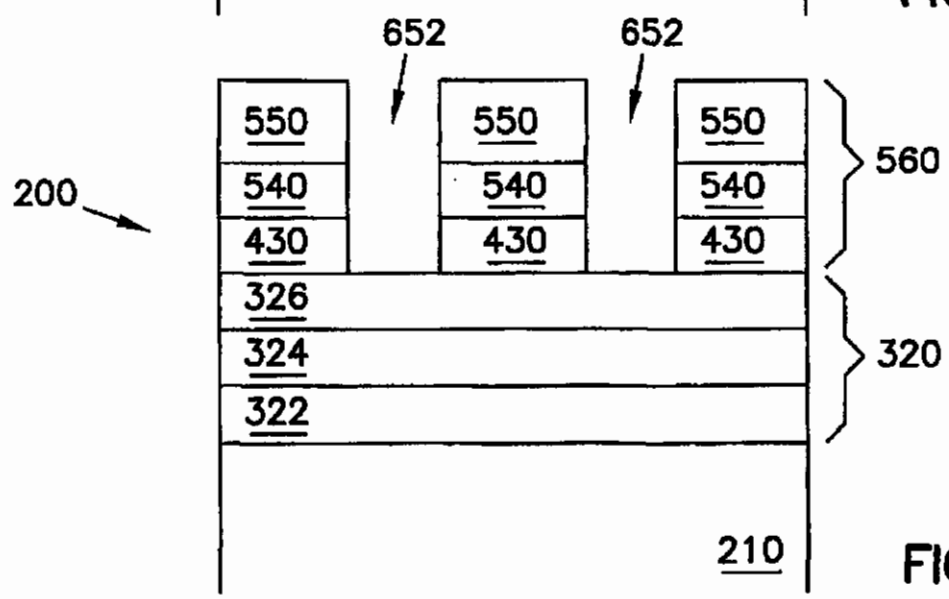



FIG. 7

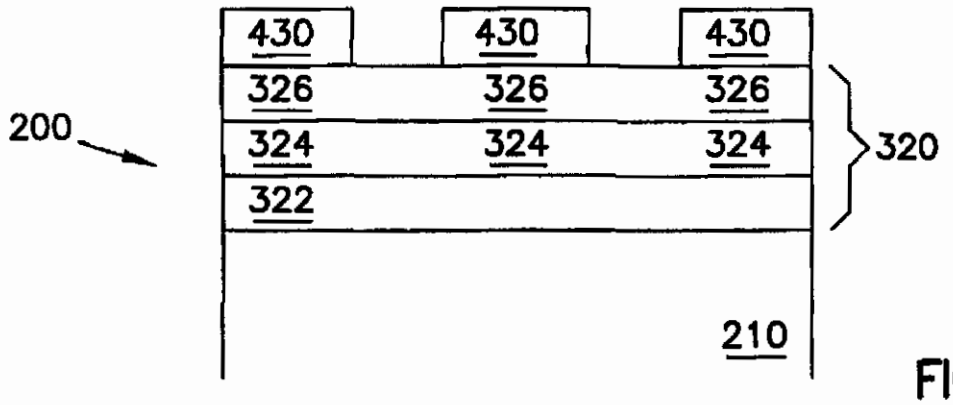



FIG. 8

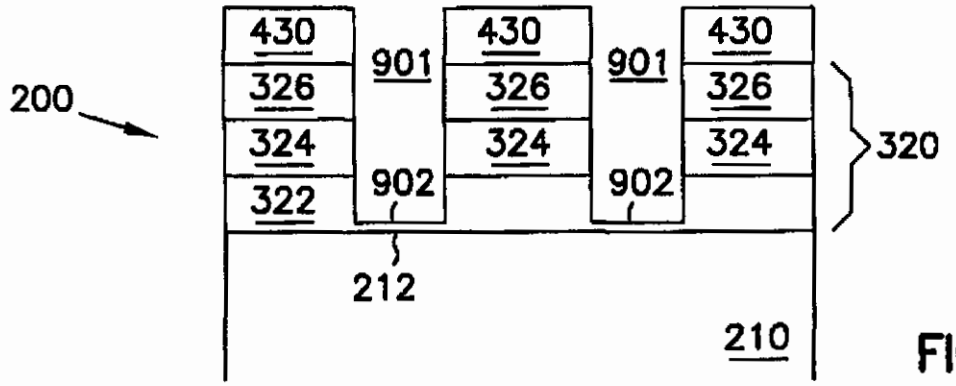



FIG. 9

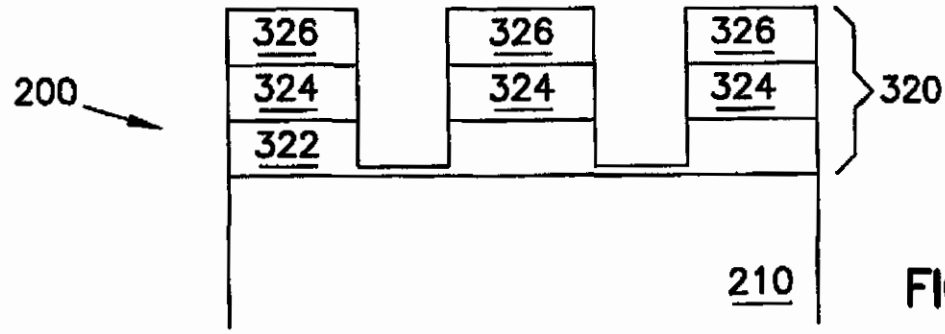



FIG. 10

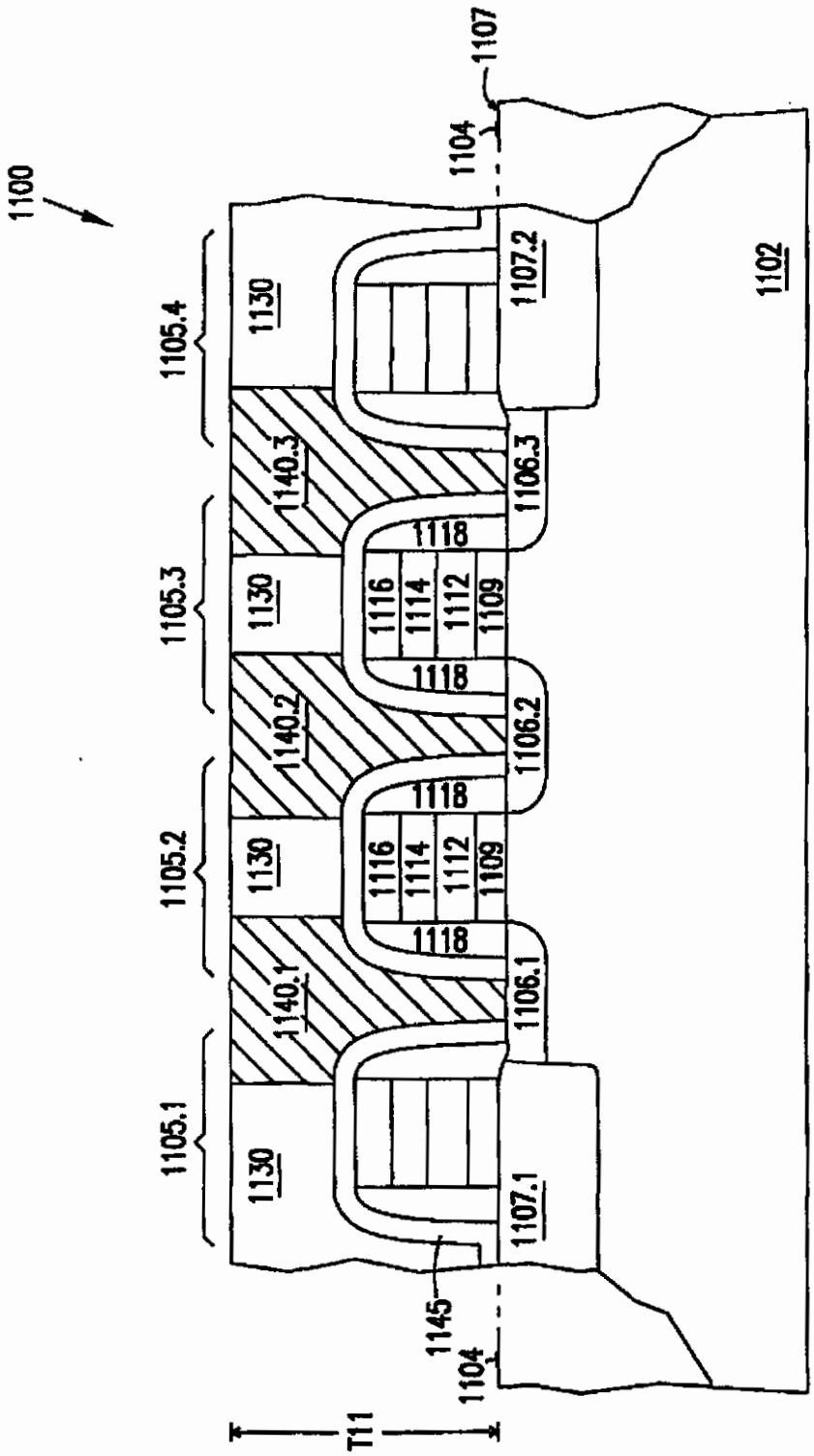

1100
1107
1104
1102
1107.2
1106.3
1106.2
1106.1
1107.1
1105.4
1105.3
1105.2
1105.1
1130
1140.3
1140.2
1140.1
1118
1116
1114
1112
1109
1145
T11

FIG. 11

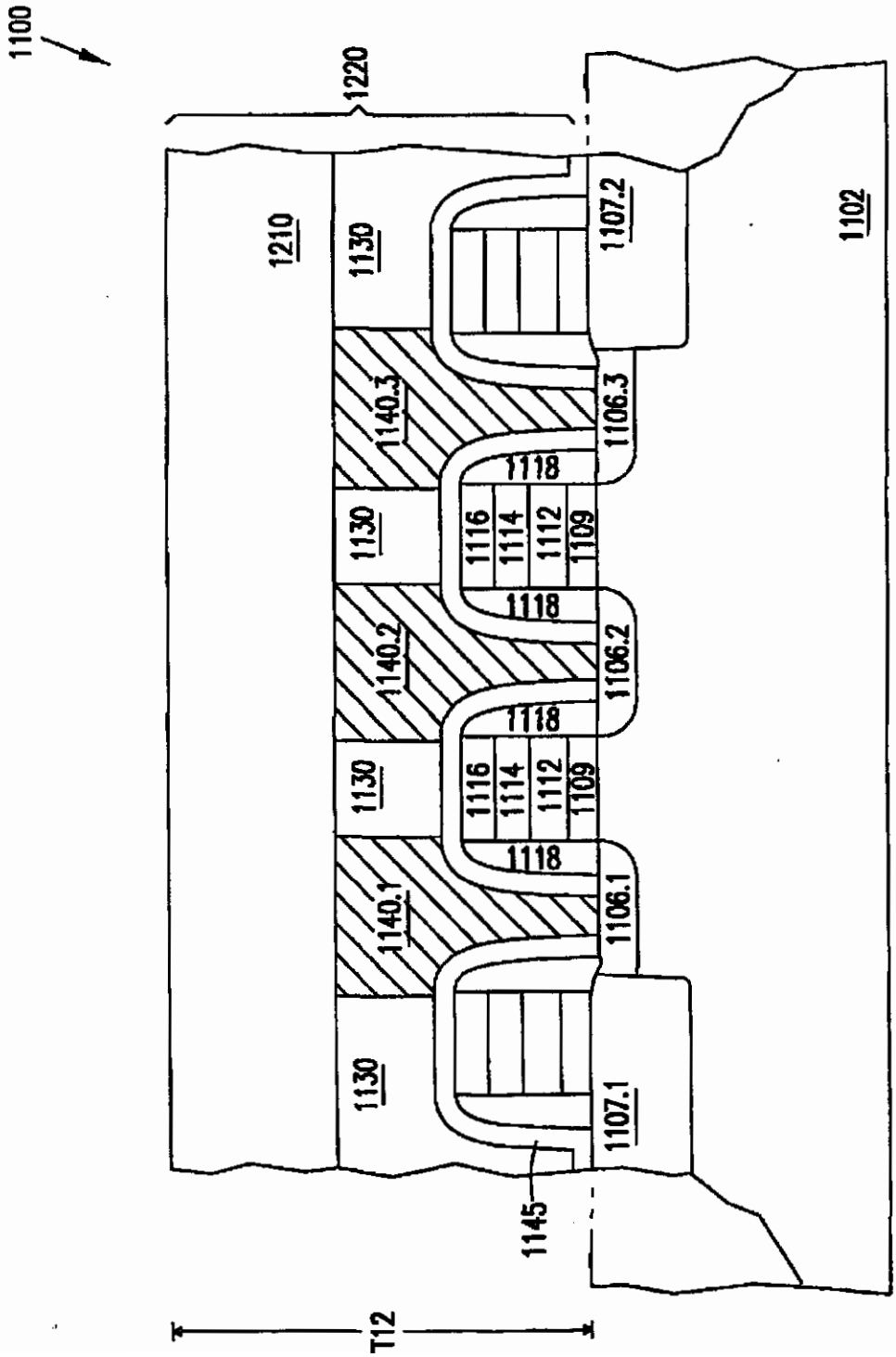

1100
1220
1210
1130
1107.2
1102
1140.3
1106.3
1118
1116
1114
1112
1109
1130
1118
1140.2
1106.2
1118
1116
1114
1112
1109
1130
1118
1140.1
1106.1
1130
1107.1
1145
T12

FIG. 12

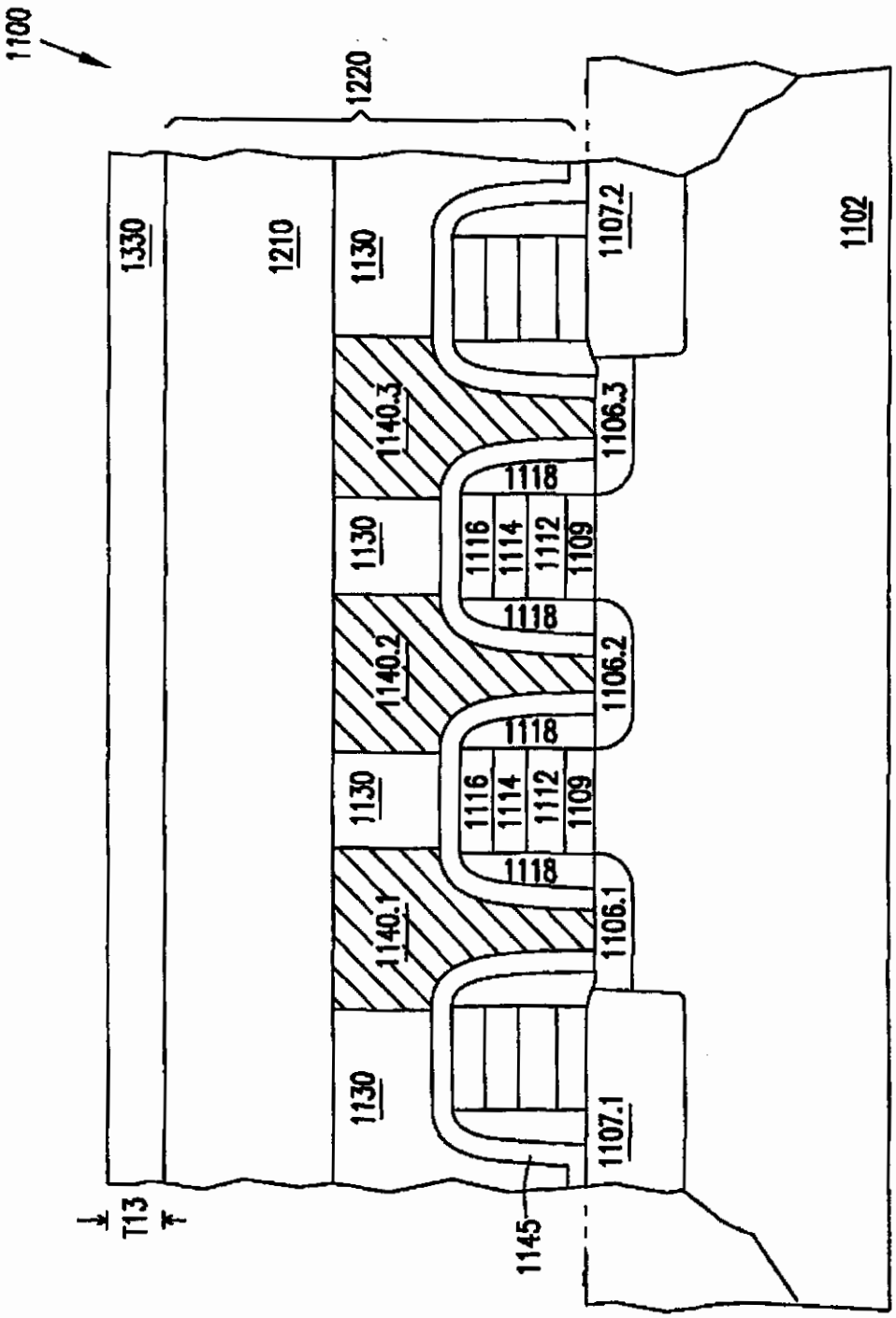

1100
1220
1330
1210
1130
1107.2
1102
1140.3
1106.3
1118
1116
1114
1112
1109
1130
1118
1140.2
1106.2
1118
1116
1114
1112
1109
1130
1118
1140.1
1106.1
1130
1107.1
T13
1145

FIG. 13

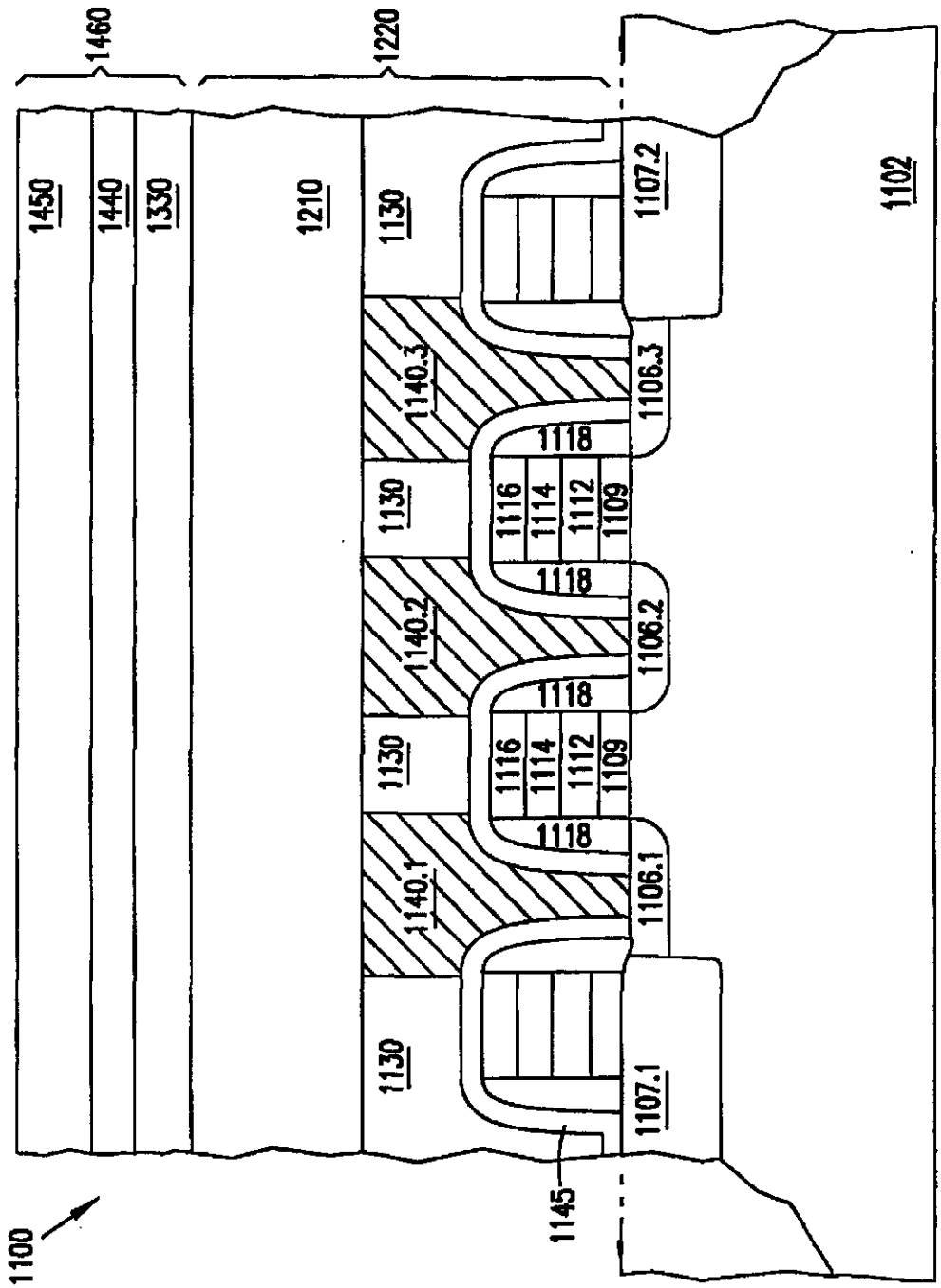

1460
1220
1450
1440
1330
1210
1130
1107.2
1102
1140.3
1106.3
1118
1116
1114
1112
1109
1130
1118
1140.2
1106.2
1118
1116
1114
1112
1109
1130
1118
1140.1
1106.1
1130
1107.1
1145
1100

FIG. 14

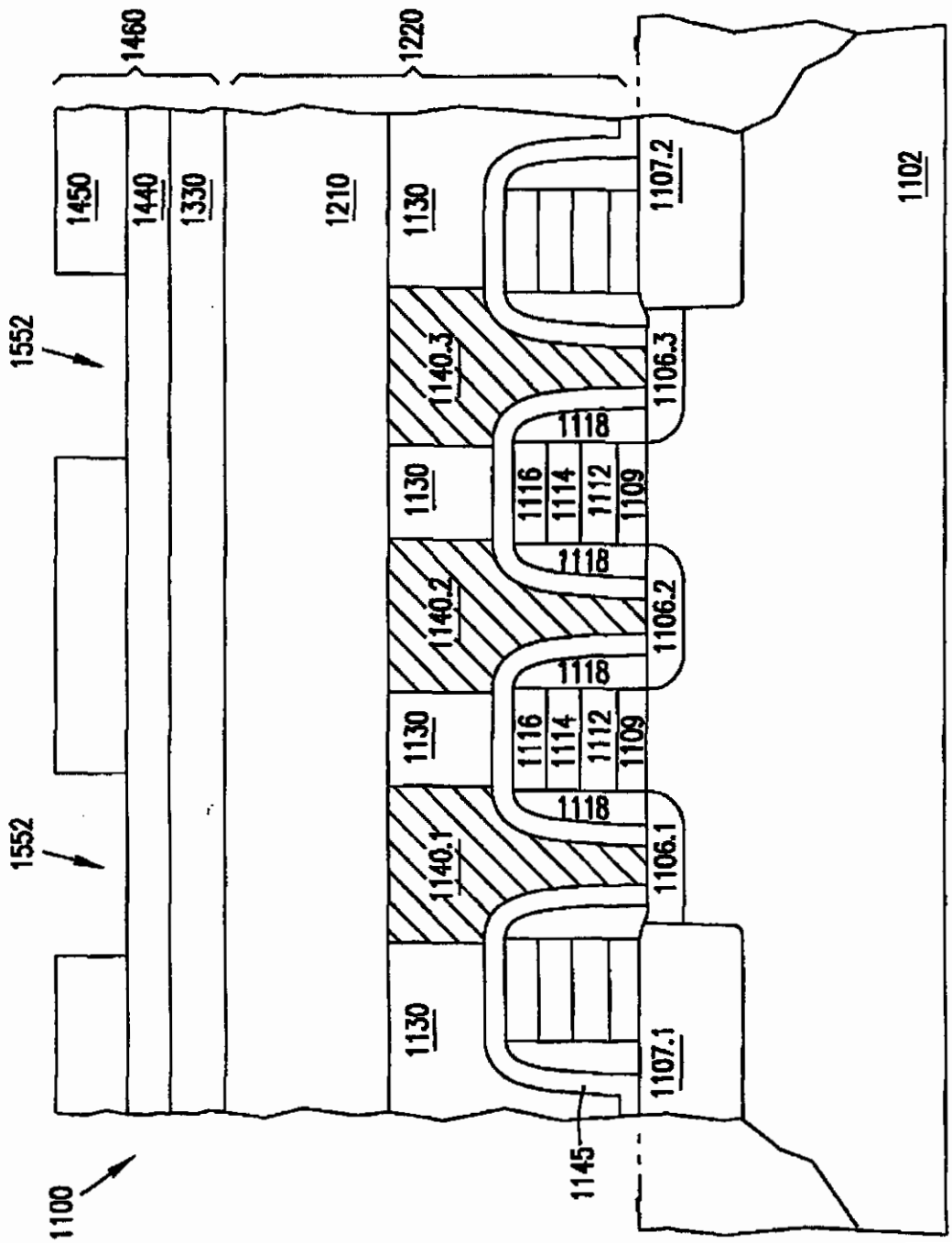

1460
1220
1450
1440
1330
1210
1130
1107.2
1102
1552
1140.3
1106.3
1118
1116
1114
1112
1109
1130
1118
1140.2
1106.2
1118
1116
1114
1112
1109
1130
1118
1552
1140.1
1106.1
1130
1107.1
1145
1100

FIG. 15

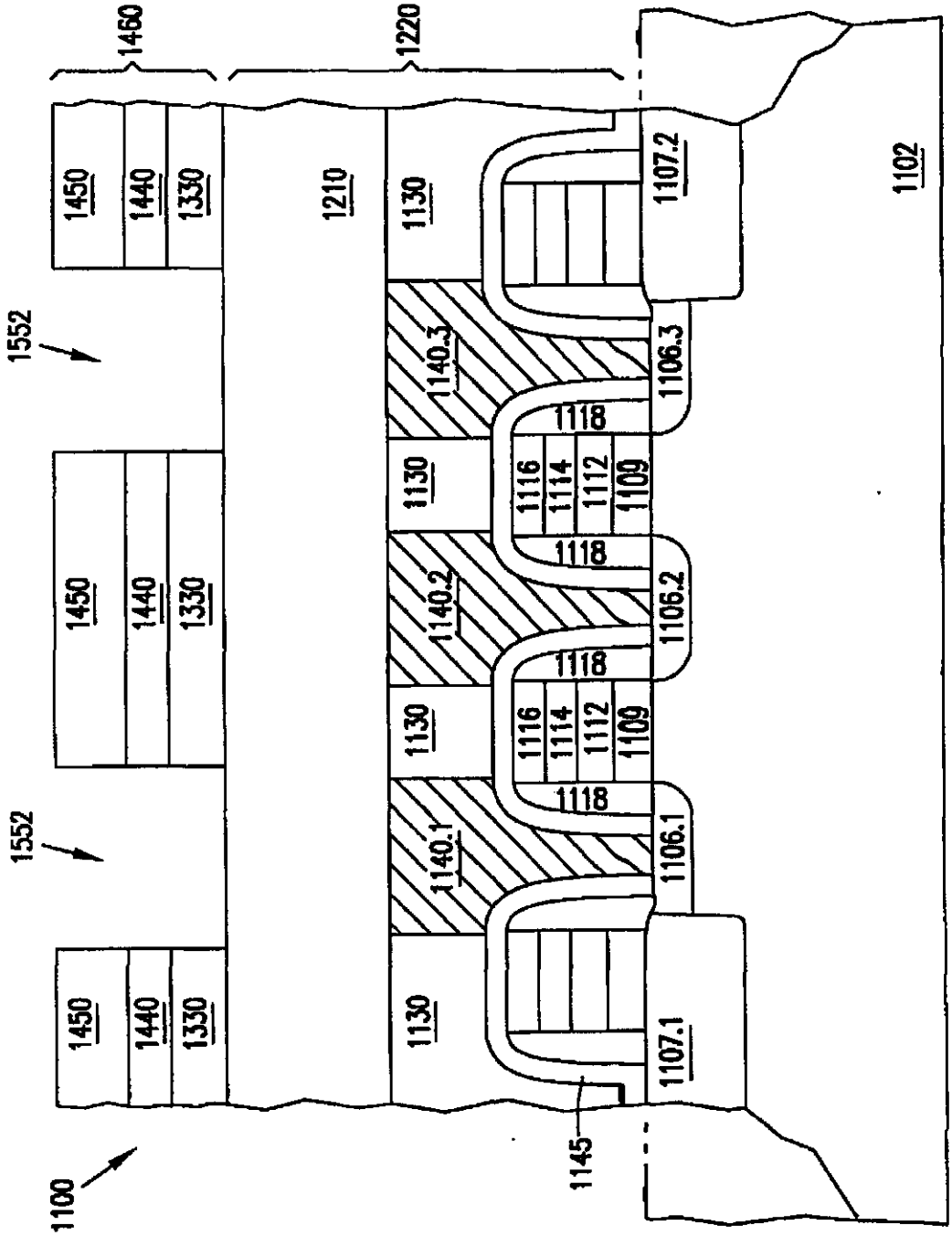

1460
1220
1450
1440
1330
1210
1130
1107.2
1102
1552
1140.3
1106.3
1118
1116
1114
1112
1109
1130
1140.2
1106.2
1118
1116
1114
1112
1109
1130
1552
1140.1
1106.1
1118
1450
1440
1330
1130
1107.1
1145
1100

FIG. 16

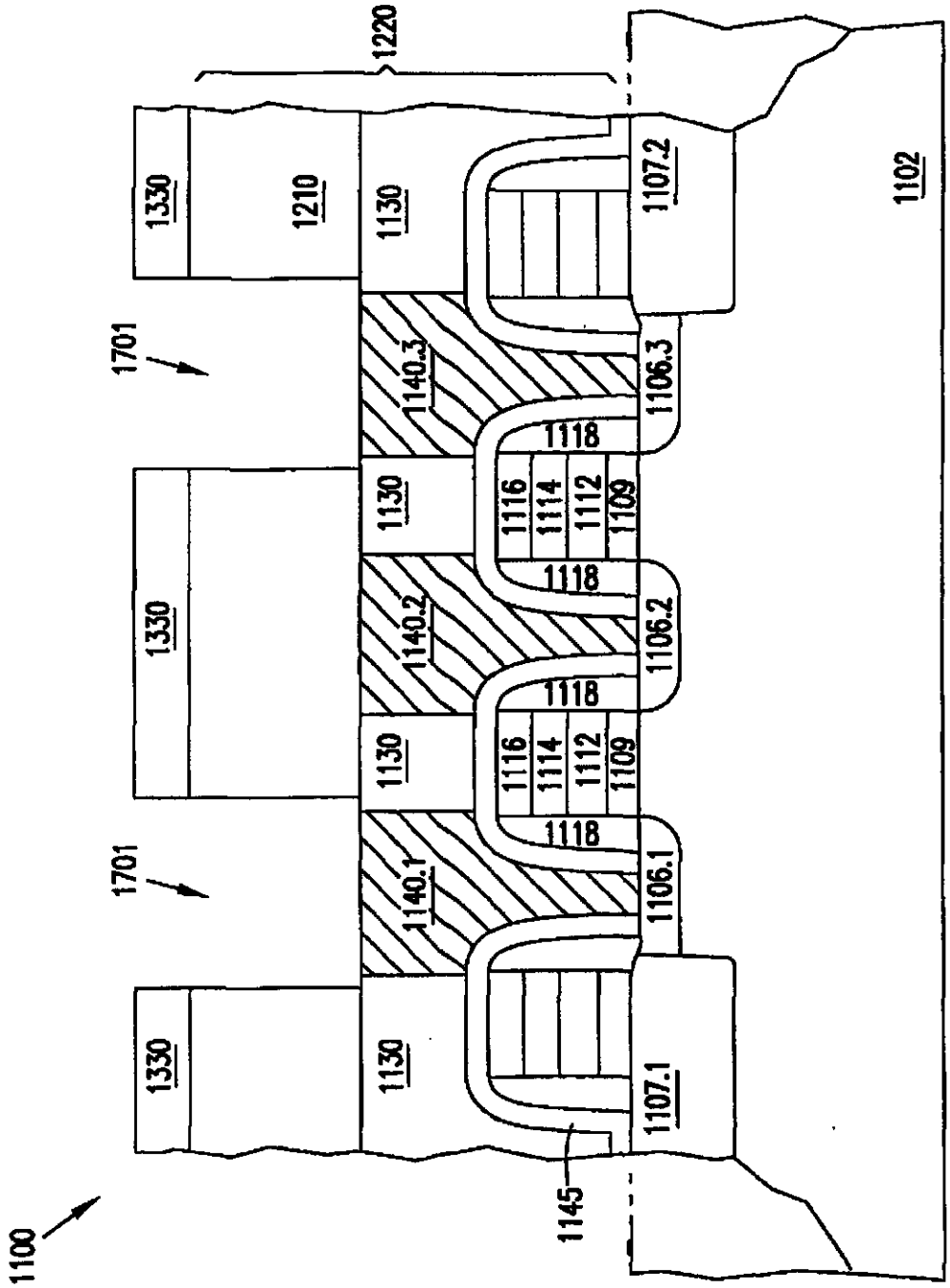

1220
1330
1210
1130
1107.2
1102
1701
1140.3
1106.3
1118
1116
1114
1112
1109
1130
1330
1140.2
1106.2
1118
1116
1114
1112
1109
1130
1701
1140.1
1106.1
1118
1330
1130
1107.1
1145
1100

FIG. 17

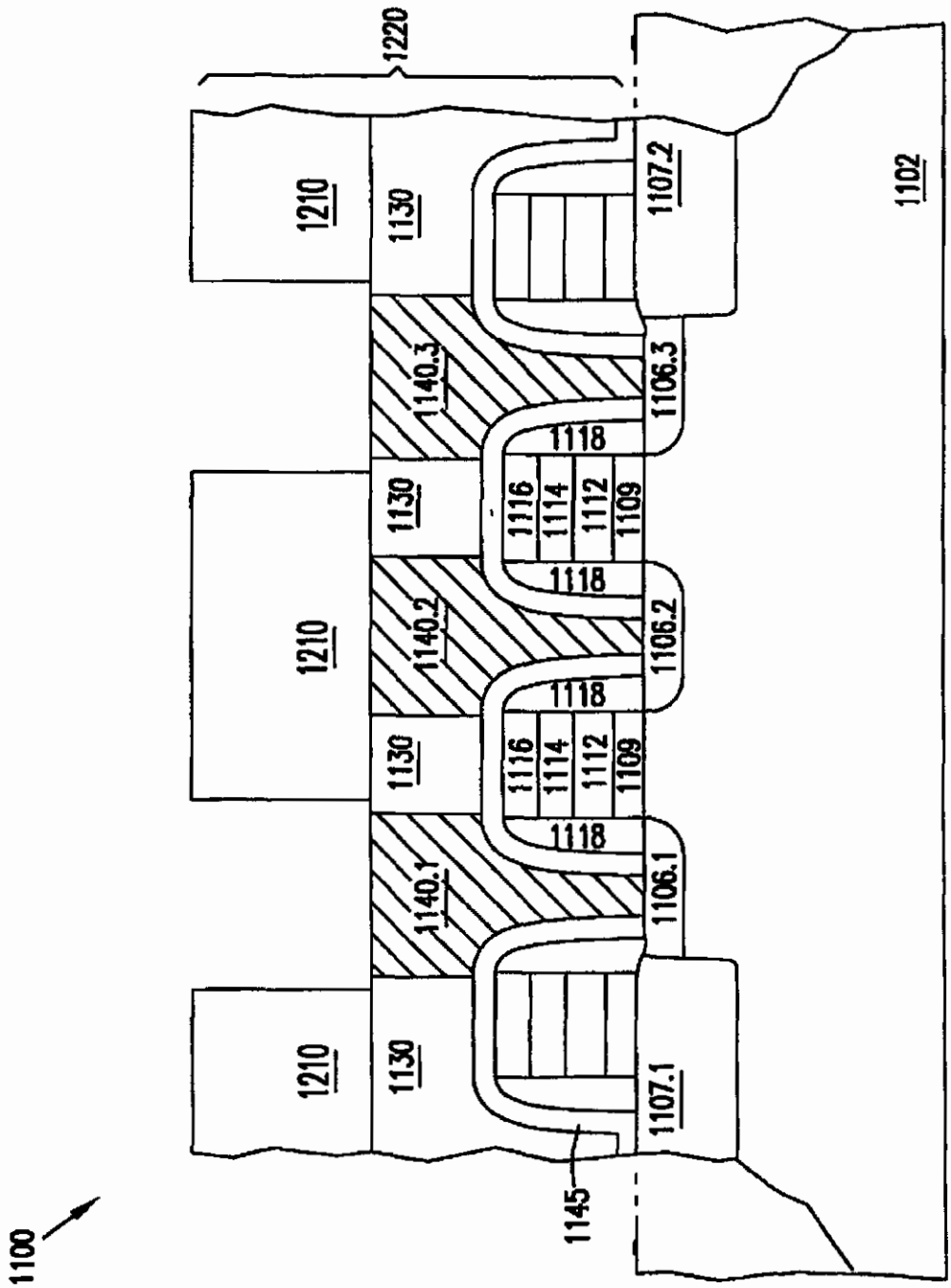

1100
1145
1220
1210
1130
1140.3
1140.2
1140.1
1107.2
1107.1
1106.3
1106.2
1106.1
1118
1116
1114
1112
1109
1102

FIG. 18

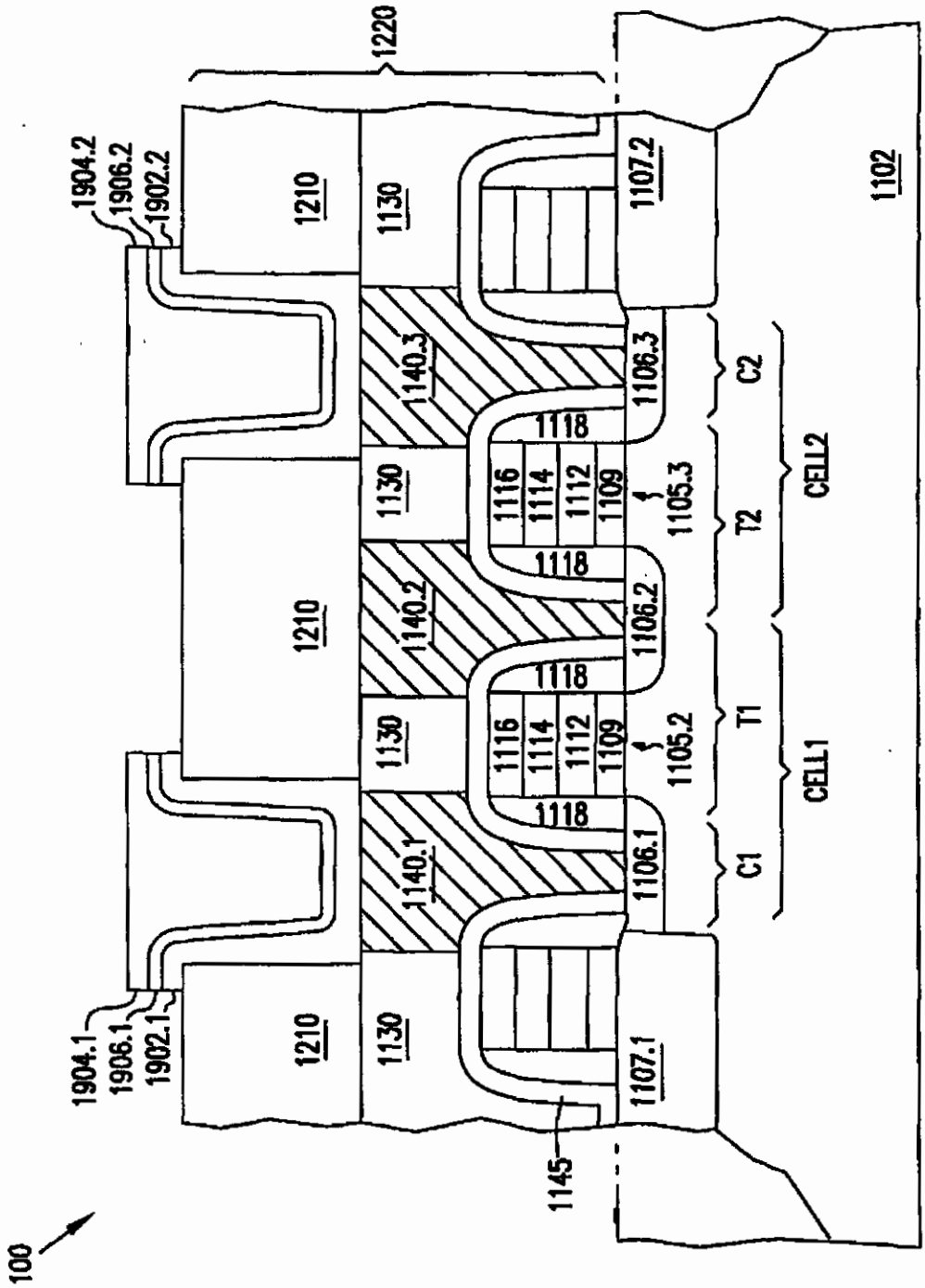

1100
1904.1
1906.1
1902.1
1904.2
1906.2
1902.2
1220
1210
1130
1140.1
1140.2
1140.3
1145
1102
1107.1
1107.2
1106.1
1106.2
1106.3
1105.2
1105.3
1118
1116
1114
1112
1109
C1
C2
T1
T2
CELL1
CELL2

FIG. 19

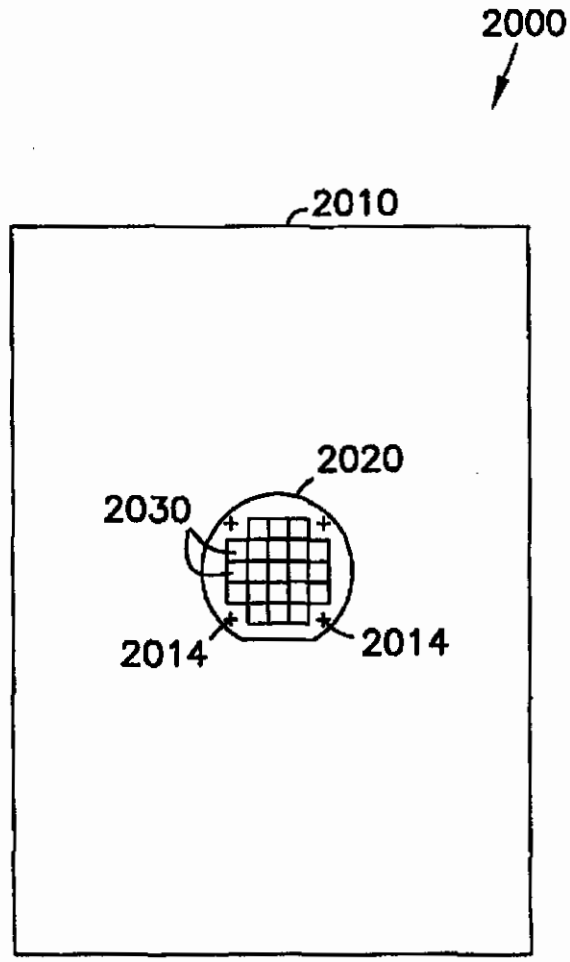



FIG. 20